

Wednesday, September 30

1F Middle-Sized Hall A	1F Middle-Sized Hall B	1F 101	1F 102	1F 107a	1F 107b	1F 108a
A-6: Optical Sensing (9:00-10:00) Chairs: N. Iizuka (Toshiba) S. Nishikawa (Mitsubishi Electric)		C-6: III-V Photovoltaics and Related Technologies (9:00-10:00) Chairs: T. Hoshii (Univ. of Tokyo) T. Negami (Panasonic)	D-6: Nanowire Synthesis and Properties I (9:00-10:15) Chairs: M. Arita (Univ. of Tokyo) N. Fukata (NIMS)	E-6: 3D / TSV (9:00-10:30) Chairs: T. Fukushima (Tohoku Univ.) M. Takeyama (Kitami Inst. of Tech.)	F-6: Advanced Memories and Circuits (9:00-10:20) Chairs: I. Akita (Toyohashi Tech) Y. Mita (Univ. of Tokyo)	
9:00 A-6-1 (Invited) Si and SiN Biophotonic Technology Platform, Applied to Biosensing, Spectroscopy, and Lens-Free Imaging <i>W. Van Roy¹, P. Neutens¹, T. Claes¹, R. Jansen¹, A. Subramanian², K. Jans¹, R. Vos¹, J. O'Callaghan¹, D. Vercruyssen¹, R. Stahl¹, V. Mukund¹, B. Du Bois¹, P. Helin¹, A. Stassen¹, S. Severi¹, D. Martens², P. Bienstman², P. Deshpande¹, R. Baets², A. Lambrechts¹, L. Lagae^{1,3}, X. Rottenberg¹ and P. Van Dorpe^{1,3}, ¹Imec, ²Ghent Univ. and ³KU Leuven (Belgium)</i>		9:00 C-6-1 (Invited) Recent Results for Concentrator Photovoltaics in Japan <i>M. Yamaguchi¹, T. Takamoto², K. Araki³ and N. Kojima¹, ¹Toyota Tech. Inst., ²Sharp Corp. and ³Daido Steel Corp. (Japan)</i>	9:00 D-6-1 (Invited) Nanowire Growth as a Means for the Monolithic Integration of III-V Compound Semiconductors on Si <i>L. Geelhaar, Paul-Drude-Institut fuer Festkoerperelektronik (Germany)</i>	9:00 E-6-1 (Invited) 3D Interconnection of Single Micron Pitch by Hybrid Bonding Technology <i>M. Nimura¹, M. Ohyama¹, S. Shoji², M. Tamura², T. Enomoto², A. Shigetou² and J. Mizuno¹, ¹Waseda Univ., ²Nissan Chemical Indus. and ³NIMS (Japan)</i>	9:00 F-6-1 39% tAC Improvement, 11% Energy Reduction, 32Kbit 1R/1W 2port SRAM using Two-stage Read Boost and Write-Boost after Read Sensing Scheme <i>Y. Yamamoto¹, S. Moriwaki¹, A. Kawasumi², S. Miyano³ and H. Shinohara⁴, ¹Socionext Inc., ²Toshiba Corp., ³STARC and ⁴Waseda Univ. (Japan)</i>	
9:30 A-6-2 Stretchable Photonic Crystal Coupled-Nanobeam Lasers for Stretch Sensing <i>C. Wang, T.W. Lu and P.T. Lee, NCTU (Taiwan)</i>		9:30 C-6-2 Terahertz Emission from Individual Subcells in a Triple Junction Solar Cell Excited by a Wavelength Tunable Pulsed Laser <i>S. Hamauchi¹, Y. Sakai¹, T. Umegaki¹, A. Ito², H. Nakanishi², I. Kawayama¹, H. Murakami¹ and M. Tonouchi¹, ¹Osaka Univ. and ²SCREEN Holdings Co., Ltd. (Japan)</i>	9:30 D-6-2 Bridging the Gap between the Nanometer-scale Bottom-up and Micrometer-scale Top-down Approaches for Site-defined InP/ InAs Heterostructure Nanowires <i>G. Zhang^{1,2}, M. Takiguchi^{1,2}, K. Tateno^{1,2} and H. Gotoh¹, ¹NTT BRL and ²NTT Nanophotonics Center (Japan)</i>	9:30 E-6-2 Evaluation of 2-D Local Stress Distribution in Stacked IC Chip Using Stress-Induced Retention Time Modulation of DRAM Cell Array <i>S. Tanikawa, H. Hashiguchi, Y. Sugawara, H. Kino, T. Fukushima, M. Koyanagi and T. Tanaka, Tohoku Univ. (Japan)</i>	9:20 F-6-2 Pure CMOS One-Time Programmable Memories using a Combination of Gate-Ox Anti-fuse and Poly-Si Fuse <i>M. Matsumoto, K. Tatsumura, K. Zaitzu and S. Yasuda, Toshiba Corp. (Japan)</i>	
9:45 A-6-3 Gold Bowtie Aperture with Projected Pad Underneath and Its Capability in Optical Sensing <i>P.Y. Chen, T.W. Lu and P.T. Lee, NCTU (Taiwan)</i>		9:45 C-6-3 Tandem Photovoltaic-photoelectrochemical Device for Solar Hydrogen Generation <i>S. Kosar¹, Y. Pihoshi², I. Turkevych^{2,4}, K. Mawatari², J. Uemura², Y. Kazoe², K. Makita³, T. Sugaya³, T. Matsui³, D. Fujita⁴, M. Tosa⁴, Y.M. Struk¹, M. Kondo³ and T. Kitamori², ¹Chernivtsi National Univ., ²Univ. of Tokyo, ³AIST and ⁴NIMS (Ukraine)</i>	9:45 D-6-3 Structural and Magnetic Characterizations of Vertical Ferromagnetic MnAs/Semiconducting InAs Heterojunction Nanowires <i>R. Kodaira, K. Kabamoto, S. Sakita and S. Hara, Hokkaido Univ. (Japan)</i>	9:50 E-6-3 Investigation of Low Temperature Cu Pillar Thermosonic Bonding for 3D Integration Applications <i>S.L. Lu¹, Y.P. Huang¹, Y.S. Huang¹, Y.H. Tseng², M.F. Shu² and K.N. Chen¹, ¹NCTU and ²ASE Group (Taiwan)</i>	9:40 F-6-3 Digitally Calibrated Dynamic Latched Comparator with Stochastic Offset Voltage Detection Technique for Low-Power ADCs <i>T. Okazawa¹, T. Kawano¹, M. Ishida^{1,2} and I. Akita¹, ¹Toyohashi Tech and ²EIIRIS (Japan)</i>	
			10:00 D-6-4 Effects of Polytypism on the Thermoelectric Properties of Si Nanowires: a Combination of Density Functional Theory and Boltzmann Transport Equation Calculations <i>T. Komoda, T. Akiyama, K. Nakamura and T. Ito, Mie Univ. (Japan)</i>	10:10 E-6-4 Novel Integration of Ultra-thin Al₂O₃ with Low-k Dielectric as Bi-layer Liner for Capacitance Optimization and Stress Mitigation in Cu-TSV <i>L. Zhang^{1,2}, H.Y. Li¹, Y. Shang², W. Yoo³, H. Yu² and C.S. Tan², ¹Inst. of Microelectronics, A*STAR, ²NTU and ³WaferMasters, Inc. (Singapore)</i>	10:00 F-6-4 No Reattaching and 8 Directions Detectable Octagonal MOSFET Stress Sensor <i>T. Harada, K. Kaiwa and Y. Yamazaki, Yamagata Univ. (Japan)</i>	

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2F 201	2F 202	2F Small Hall	2F 204	2F 206	2F 207	1F 108b
H-6: Quantum Optics (9:00-10:15) Chairs: T. Tanamoto (Toshiba) T. Nakaoka (Sophia Univ.)	J-6: SiC MOS (9:00-10:15) Chairs: D. Hisamoto (Hitachi) C.-F. Huang (National Tsing Hua Univ.)	K-6: Physics (9:00-10:00) Chairs: N. Mori (Osaka Univ.) M. Hane (Renesas Electronics)	M-6: Oxide Devices (9:00-10:00) Chairs: K. Maezawa (Univ. of Toyama) M. Kuzuhara (Univ. of Fukui)	N-6: 2D Materials and Band Engineering (9:00-10:10) Chairs: O. Nakatsuka (Nagoya Univ.) T. Aoyama (Toshiba)	O-6: NAND Flash Device (9:00-10:30) Chairs: K. Yamamoto (Toshiba) K. Hamada (Micron Memory Japan)	
9:00 H-6-1 (Invited) Quantum Communications with Semiconductor Devices <i>R.M. Stevenson, Toshiba Research Europe (UK)</i>	9:00 J-6-1 (Invited) Threshold-Voltage Instability in SiC MOSFETs <i>A. Lelis, R. Green and D. Habersat, U.S. Army Res. Lab. (USA)</i>	9:00 K-6-1 Modeling of Nonlinear Thermal Resistance in FinFET <i>B.K. Kompala¹, P. Kushwaha¹, S. Khandelwal², J.P. Duarte², A.S. Medury², C. Hu² and Y.S. Chauhan¹, ¹IIT Kanpur and ²Univ. of California Berkeley (India)</i>	9:00 M-6-1 Improved Performance of α-IGZO Thin-Film Transistors with an Au/ HfSiO/IGZO(O₂-rich) Schottky Source <i>C.H. Hung¹, S.J. Wang¹, Y.H. Chen¹, C.H. Wu², C. Lin¹, P.Y. Liu¹, Y.C. Tu¹ and T.H. Lin¹, ¹NCKU and ²Chung Hua Univ. (Taiwan)</i>	9:00 N-6-1 (Invited) High Performance Electronics Based on Novel Two Dimensional Materials <i>Y. Wu, Huazhong Univ. of Sci. and Tech. (China)</i>	9:00 O-6-1 (Invited) Future Prospects of Data Storage Technologies: NAND Flash Memory and Storage Class Memory Hybrid System <i>K. Takeuchi, Chuo Univ. (Japan)</i>	
9:30 H-6-2 Electron Spin Coherence Time of Nitrogen- Vacancy Center in Diamond Improved by External Electric Field <i>S. Kobayashi^{1,2}, H. Morishita¹, Y. Matsuzaki³, S. Miwa¹, Y. Suzuki¹ and N. Mizuochi^{1,2}, ¹Osaka Univ., ² JST-CREST and ³NTT BRL (Japan)</i>	9:30 J-6-2 Threshold Voltage Instability in 4H-SiC MOSFETs with Nitrided Gate Oxide Revealed by Non-relaxation Method <i>M. Sometani^{1,2}, D. Okamoto², S. Harada², H. Ishimori², S. Takasu², T. Hatakeyama², M. Takei^{1,2}, Y. Yonezawa², K. Fukuda² and H. Okumura², ¹Fuji Electric Co., Ltd. and ²AIST (Japan)</i>	9:20 K-6-2 Ballistic and Quasi- ballistic Hole Transport Properties in Germanium Nanowire pMOSFETs Based on an Extended "Top of the Barrier" Model <i>H. Tanaka, J. Suda and T. Kimoto, Kyoto Univ. (Japan)</i>	9:15 M-6-2 Correlation between Crystallinity and Formation of Oxygen Vacancies in IGZO - Comparison between Crystal and Amorphous Using First-Principles Calculations - <i>T. Hiramatsu, M. Nakashima, E. Kikuchi, N. Ishihara, M. Tsubuku, K. Dairiki and S. Yamazaki, Semiconductor Energy Lab. Co., Ltd. (Japan)</i>	9:30 N-6-2 Two Dimensional Si- Based Semiconductor Si_{1-y}C_y: C Atom Induced Band Structure Modulation at Visible Region <i>T. Mizuno¹, Y. Nagamine¹, U. Omata¹, Y. Suzuki¹, W. Urayama¹, T. Aoki¹ and T. Sameshima², ¹Kanagawa Univ. and ²Tokyo Univ. of Agri. & Tech. (Japan)</i>	9:30 O-6-2 Effects of Cell V_{th} State and Number of Traps on Statistical Distribution of Random Telegraph Noise in Scaled NAND Flash Memory <i>T. Tomita and K. Miyaji, Shinshu Univ. (Japan)</i>	
9:45 H-6-3 Photon Correlation Study of Background Suppressed Single InGaN Nanocolumns <i>T. Yamamoto, M. Maekawa, Y. Imanishi, S. Ishizawa, T. Nakaoka and K. Kishino, Sophia Univ. (Japan)</i>	9:45 J-6-3 Effect of Nitridation for SiO₂/SiC Interface on Defects Properties near Conduction Band Edge <i>W. Takeuchi¹, K. Yamamoto², M. Sakashita¹, T. Kanemura², O. Nakatsuka¹ and S. Zaima¹, ¹Nagoya Univ. and ²DENSO Corp. (Japan)</i>	9:40 K-6-3 Experimental Study on Interface Region of Two- Dimensional Si Layers <i>T. Mizuno¹, Y. Suzuki¹, R. Kikuchi¹, A. Suzuki¹, M. Yamanaka¹, Y. Nagamine¹, T. Aoki¹ and T. Maeda², ¹Kanagawa Univ. and ²AIST (Japan)</i>	9:30 M-6-3 Ideal Deep-Subthreshold Characteristics in C-Axis Aligned Crystalline Oxide Semiconductor FET <i>D. Matsubayashi, M. Tsubuku, T. Takeuchi, S. Matsuda, K. Ohshima, T. Tanaka, A. Shimomura, M. Sakakura, Y. Yamamoto and S. Yamazaki, Semiconductor Energy Lab. Co., Ltd. (Japan)</i>	9:50 N-6-3 Chemical Trend of Isoelectronic Traps in Si Tunnel FET; First- Principles Study <i>S. Iizuka and T. Nakayama, Chiba Univ. (Japan)</i>	9:50 O-6-3 Improvement of Cell VT Distribution & Program Disturbance of NAND Flash Device by Using Tilt Implantation for Cell Junction Counter Doping <i>D.Y. Kim, N.K. Kim, K.T. Lee, H.Y. Shim, S.K. Park, B.K. Kim, K.B. Lee, H.Y. Chang, K.O. Ahn and J.W. Kim, SK Hynix Inc. (Korea)</i>	
10:00 H-6-4 Tolerance of Photon Entanglement in a Droplet Epitaxial Quantum Dot Grown on (111)A Surface <i>H. Nakajima¹, X. Liu², N. Ha², R. Takemoto¹, H. Kurosawa¹, T. Mano², T. Kuroda², K. Sakoda², I. Suemune¹ and H. Kumano¹, ¹Hokkaido Univ. and ²NIMS (Japan)</i>	10:00 J-6-4 Origin of Low Channel Mobility and Threshold Voltage Instability of SiC-MOSFETs <i>H. Shiomi¹, H. Kitai¹, M. Tsujiyama¹, Y. Kiuchi¹, D. Nakata², S. Ono², K. Kojima¹, K. Fukuda¹, K. Sakamoto¹, K. Yamasaki² and H. Okumura¹, ¹AIST and ²New JRC (Japan)</i>		9:45 M-6-4 Trench Gate Process for 60-nm-Node C-Axis Aligned Crystalline In- Ga-Zn-O Field-Effect Transistors <i>Y. Asami, A. Shimomura, Y. Okazaki, D. Matsubayashi, M. Tsubuku, M. Kurata, S. Okamoto, S. Sasagawa, T. Moriwaka, T. Kakehata, Y. Yakubo, K. Kato, Y. Yamamoto and S. Yamazaki, Semiconductor Energy Lab. Co., Ltd. (Japan)</i>		10:10 O-6-4 A New High Density FinFET OTP Technology <i>P.C. Peng¹, Y.Z. Chen¹, H.W. Pan¹, W.Y. Hsiao², K.H. Chen², Y.H. Kuo², C.P. Lin², B.Z. Tien², T.S. Chang², Y.C. King¹ and C.J. Lin¹, ¹National Tsing Hua Univ. and ²TSMC (Taiwan)</i>	

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1F Middle-Sized Hall A	1F Middle-Sized Hall B	1F 101	1F 102	1F 107a	1F 107b	1F 108a
A-7: III-V Devices and Related Technologies (10:45-12:30) Chairs: T. Isu (Tokushima Univ.) T. Shimizu (PETRA)		C-7: Crystalline Silicon Photovoltaics (10:45-12:30) Chairs: M. Isomura (Tokai Univ.) L.-S.Hong (TECRO in Japan)	D-7: Nanowire Synthesis and Properties II (10:45-12:30) Chairs: H. Tatsuoka (Shizuoka Univ.) A. Kikuchi (Sophia Univ.)	E-7: Advanced Circuits and MEMS Integration (10:45-12:35) Chairs: J. C. Guo (NCTU) M. Ueki (Renasas Electronics)	F-7: Biosensors (10:45-12:30) Chairs: C.-S. Lai (Chang Gung Univ.) T. Tanaka (Tohoku Univ.)	G-7: Organic Devices II (10:45-12:45) Chairs: K. Fujita (Kyushu Univ.) T. Shimada (Hokkaido Univ.)
10:45 A-7-1 Heterogeneous Quantum Dots/Silicon Photonics Wavelength Tunable Laser Diode <i>T. Kita¹, N. Yamamoto², T. Kawanishi² and H. Yamada¹, ¹Tohoku Univ. and ²NICT (Japan)</i>		10:45 C-7-1 Formation of Thermally Stable a-Si Passivation Films using Liquid Si <i>C. Guo¹, K. Ohdaira¹, H. Takagishi² and T. Shimoda¹, ¹JAIST and ²Fukushima Univ. (Japan)</i>	10:45 D-7-1 (Invited) Self-assembled Functional Nanocomposites <i>Y.H. CHU, NCTU (Taiwan)</i>	10:45 E-7-1 (Invited) Manufacturing Technology of All-solid-state Thin-film Lithium Secondary Battery for Stand-alone MEMS/ Sensor Applications <i>K Suu, ULVAC, Inc. (Japan)</i>	10:45 F-7-1 (Invited) Ultrasensitive Sensors Using Enhanced Surface Plasmon Resonances in Capped Metallic Nanostructures <i>K.L. Lee¹ and P.K. Wei^{1,2}, ¹Academia Sinica and ²National Yang-Ming Univ. (Taiwan)</i>	10:45 G-7-1 (Invited) Controlling Light at the Nano-Scale via Molecular Tunnel Junctions <i>C.A. Nijhuis, NUS (Singapore)</i>
11:00 A-7-2 Waveguide InGaAs Metal-semiconductor-metal Photodetector Monolithically Integrated with InP Grating Coupler on III-V CMOS Photonics Platform <i>Y.P. Cheng^{1,2}, Y. Ikku^{1,2}, M. Takenaka^{1,2} and S. Takagi^{1,2}, ¹Univ. of Tokyo and ²JST-CREST (Japan)</i>		11:00 C-7-2 Investigation of Interface State Density and Fixed Charge of Sr,SiO_x2 on the 2×1 Sr-reconstructed Si Substrate <i>S. Taniwaki¹, Y. Hotta^{1,3}, H. Yoshida^{1,3}, K. Arafune^{1,3}, A. Ogura^{2,3} and S. Satoh^{1,3}, ¹Univ. of Hyogo, ²Meiji Univ. and ³JST-CREST (Japan)</i>	11:15 D-7-2 Fabrication of Vertical Ge Nanowires on Amorphous Substrates by Combining Au-seeded Chemical-Vapor Deposition with Al-induced Crystallization <i>M. Nakata¹, K. Toko¹, W. Jevasuwani², N. Fukata² and T. Suemasu¹, ¹Univ. of Tsukuba and ²NIMS (Japan)</i>	11:15 E-7-2 Novel Gain-Controlled Sensor Circuits Designed by Multi-physics Simulation for CMOS-MEMS Accelerometer <i>T. Konishi¹, D. Yamane^{2,4}, M. Takayasu^{2,4}, S. Dosho^{2,4}, N. Ishihara^{2,4}, K. Masu^{2,4}, H. Toshiyoshi^{3,4} and K. Machida^{1,2,4}, ¹NTT AT, ²Tokyo Tech, ³Univ. of Tokyo and ⁴JST-CREST (Japan)</i>	11:15 F-7-2 An Implantable Needle-like Shaped Device and Its Performance in Lensless Fluorescence Imaging of Biological Tissues <i>H. Takehara, Y. Ohta, M. Motoyama, M. Haruta, T. Noda, K. Sasagawa, T. Tokuda and J. Ohta, NAIST (Japan)</i>	11:15 G-7-2 Detection of Mercury (II) Ion in Water using an Organic Field Effect Transistor with a Cysteine-functionalized Gold Electrode <i>T. Minami, T. Minamiki and S. Tokito, Yamagata Univ. (Japan)</i>
11:15 A-7-3 1.3 μm Photoluminescence from InAs/GaAs Quantum Dots on CMOS-compatible (001) Silicon by Metal-organic Chemical Vapor Deposition <i>Y. Wan, Q. Li, Y. Geng and K.M. Lau, HKUST (China)</i>		11:15 C-7-3 Temperature-Dependent Minority Carrier Lifetime of Crystalline Silicon Wafers Passivated by High Quality Amorphous Silicon Oxide <i>M. Inaba, S. Todoroki, K. Nakada and S. Miyajima, Tokyo Tech (Japan)</i>	11:30 D-7-3 Catalyst-free Growth of In_xGa_{1-x}As/InAs Coaxial Nanorod Heterostructures on Graphene Layers Using Molecular Beam Epitaxy <i>Y. Tehoe, J. Jo, M. Kim and G.-C. Yi, Seoul National Univ. (Korea)</i>	11:35 E-7-3 Zeolite-trench-embedded Micro Cantilevers for CMOS Strain-gauge Integrated Gas Sensors <i>S. Inoue¹, R. Setoguchi¹, M. Denoua², S. Mintova² and Y. Mita¹, ¹Univ. of Tokyo and ²Normandie Univ. (Japan)</i>	11:30 F-7-3 In situ Monitoring of Extracellular Matrix Based on Chondrocytes Behavior using Biologically-coupled Field Effect Transistor <i>H. Satake¹, A. Saito¹, T. Kajisa², S. Mizuno³ and T. Sakata¹, ¹Univ. of Tokyo, ²PROVIGATE Inc. and ³Harvard Medical School (Japan)</i>	11:30 G-7-3 Highly Flexible Complementary Inverter with Pentacene/a-IGZO Hybrid Thin Film Transistors <i>Z. Pei, H.C. Lai and B.J. Tzeng, National Chung Hsing Univ. (Taiwan)</i>
11:30 A-7-4 Optical and Electronic Properties of Ga(N,As,P) Quantum Wells on Silicon for Laser Application <i>S. Gies, S. Karrenberg, M. Zimprich, T. Wegele, C. Kruska, A. Beyer, W. Stolz, K. Volz and W. Heimbrod, Philipps Univ. Marburg (Germany)</i>		11:30 C-7-4 Investigation of New Stacking Surface Passivation Structures with Interfacial Tuning Layers on p-type Crystalline Silicon for Solar Cell Applications <i>N. Ikeno^{1,4}, T. Katsumata^{1,2}, H. Yoshida^{3,5}, K. Arafune^{3,5}, S. Satoh^{3,5}, T. Chikyow² and A. Ogura^{1,5}, ¹Meiji Univ., ²NIMS, ³Univ. of Hyogo, ⁴JSPS Research Fellow and ⁵JST-CREST (Japan)</i>	11:45 D-7-4 Two Different Mechanisms for Au-free Growth of InAsSb Nanowires on Si Substrate <i>W.N. Du¹, X.G. Yang¹, H.Y. Pan¹, X.Y. Wang¹, X.H. Ji¹, Z.G. Wang¹, H.Q. Xu² and T. Yang¹, ¹Chinese Academy of Sciences and ²Peking Univ. (China)</i>	11:55 E-7-4 S-Parameter Characterization and Lumped-Element Modelling of mm-Wave Single-Drift IMPATT Diode <i>W. Zhang¹, Y. Yamamoto², M. Oehme¹, K. Matthies¹, B. Tillack^{2,3}, E. Kasper¹ and J. Schulze¹, ¹Univ. of Stuttgart, ²IHP Microelectronics and ³TU Berlin (Germany)</i>	11:45 F-7-4 Robust and High Sensitive Myoelectric Signal Detection utilizing Stochastic Resonance with Carbon Nanotube Composite Paper-based Surface Electrodes <i>K. Shirata¹, S. Kasai¹, T. Oya¹, Y. Hagiwara³, S. Kaeriyama² and H. Nakamura², ¹Hokkaido Univ., ²Yokohama National Univ. and ³STARC (Japan)</i>	11:45 G-7-4 Anodization Patterning for Organic Electronic Circuits with Low Operation Voltage <i>T. Yokota^{1,2}, T. Sekitani^{2,3} and T. Someya^{1,2}, ¹Univ. of Tokyo, ²JST-ERATO and ³Osaka Univ. (Japan)</i>
11:45 A-7-5 The Influence of III-V on Insulator Structure on Quantum Well Intermixing <i>S. Takashima^{1,2}, Y. Ikku^{1,2}, M. Takenaka^{1,2} and S. Takagi^{1,2}, ¹Univ. of Tokyo and ²JST-CREST (Japan)</i>		11:45 C-7-5 Catalytic Doping of Phosphorus and Boron Atoms onto Hydrogenated Amorphous Silicon Films <i>J. Seto^{1,2}, K. Ohdaira^{1,2} and H. Matsumura^{1,2}, ¹JAIST and ²JST-CREST (Japan)</i>	12:00 D-7-5 Formation of Self-aligned Pore Arrays on n-GaN Substrates by Photo-assisted Electrochemical Etching Process <i>Y. Kumazaki, T. Sato and Z. Yatabe, Hokkaido Univ. (Japan)</i>	12:15 E-7-5 Analysis and Reduction of Leakage Current of 2kV Monolithic Isolator with Wide Trench Spiral Isolation Structure <i>Y. Takeuchi, R. Kuroda and S. Sugawa, Tohoku Univ. (Japan)</i>	12:00 F-7-5 Respiratory Sensor Measuring Capacitance Constructed Across Skin <i>M. Terasawa, S. Kumagai and M. Sasaki, Toyota Tech. Inst. (Japan)</i>	12:00 G-7-5 Pseudo-CMOS Gain Enhancement by Post-Annealing Organic Circuits on Ultrathin Plastic Substrates <i>A. Reuveny^{1,2}, T. Yokota^{1,2}, S. Lee^{1,2}, R. Shidachi^{1,2}, T. Sekitani^{1,2,3} and T. Someya^{1,2}, ¹Univ. of Tokyo, ²JST-ERATO and ³Osaka Univ. (Japan)</i>

Wednesday, September 30

2F 201	2F 202	2F Small Hall	2F 204	2F 206	2F 207	1F 108b
H-7: Quantum Devices (10:45-12:30) Chairs: A. Otiwa (Osaka Univ.) T. Nakaoka (Sophia Univ.)		K-7: Characterization II (10:45-12:05) Chairs: N. Sugii (Hitachi) T.-S. Chao (NCTU)	M-7: III-V Materials & Devices (10:45-12:30) Chairs: N. Hara (Fujitsu Labs.) T. Suzuki (JAIST)		O-7: ReRAM 2 (10:45-12:05) Chairs: K. Kinoshita (Tottori Univ.) H. Hwang (POSTECH)	
10:45 H-7-1 Determination of Phonon Decay-rate in p-type Si under Fano Resonance by Measurements of Coherent Phonons with Femto-second Laser Pulses <i>K. Kato, K. Oguri, H. Sanada, T. Tawara, T. Sogawa and H. Gotoh, NTT BRL (Japan)</i>		10:45 K-7-1 Reliability of Improved CAAC-IGZO FET Satisfying NOSRAM Performance <i>T. Murakawa, K. Ohshima, M. Tsubuku, D. Shimada, N. Kamata, T. Tanaka, A. Shimomura, M. Sakakura, Y. Yamamoto and S. Yamazaki, Semiconductor Energy Lab. Co. Ltd. (Japan)</i>	10:45 M-7-1 (Invited) THz Devices Based on 2D Electron Systems <i>H.G. Xing, R. Yan, B. Song, J. Encomendero and D. Jena, Cornell Univ. (USA)</i>		10:45 O-7-1 Low Power Switching of Si-doped Ta₂O₅ ReRAM for High Density Memory Application <i>B.Y. Kim, K.J. Lee, S.O. Chung, S.G. Kim and H.S. Kim, SK Hynix Inc. (Korea)</i>	
11:00 H-7-2 Dynamic creation of a topologically-ordered Hamiltonian using spin-pulse control in the Heisenberg model <i>T. Tanamoto¹, K. Ono², Y.X. Liu^{2,3} and F. Nori^{2,4}, ¹Toshiba Corp., ²RIKEN, ³Tsinghua Univ. and ⁴Univ. of Michigan (Japan)</i>		11:05 K-7-2 Degradation Investigation of High-k/Metal Gate nMOSFETs by 3D KMC with Multiple Traps Interactions <i>Y. Li, H. Jiang, Z.Y. Lun, Y.J. Wang, P. Huang, H. Hao, G. Du, X. Zhang and X.Y. Liu, Peking Univ. (China)</i>	11:15 M-7-2 Electrical Characteristics of Au/Ni Schottky Diodes on Cleaved m-Plane Surfaces of Free-Standing n-GaN Substrates <i>M. Naganawa¹, T. Aoki¹, T. Mishima² and K. Shiojima¹, ¹Univ. of Fukui and ²Hosei Univ. (Japan)</i>		11:05 O-7-2 Interface Engineered HfO₂-Based 3D Vertical Resistive Random Access Memory with Forming-Free Operation <i>B. Hudec¹, I.T. Wang¹, W.L. Lai¹, C.C. Zhang¹, T.H. Hou¹, P. Jancovic², K. Frohlich², M. Micusik² and M. Omastova², ¹NCTU and ²Slovak Academy of Sciences (Taiwan)</i>	
11:15 H-7-3 (Late News) Withdrawn		11:25 K-7-3 Estimation of Soft Error Tolerance According to the Thickness of Buried Oxide and Body Bias 28-nm and 65-nm in FD-SOI Processes by a Monte-Carlo Simulation <i>K. Zhang, J. Yamaguchi, S. Kanda, J. Furuta and K. Kobayashi, Kyoto Inst. of Tech. (Japan)</i>	11:30 M-7-3 Net Acceptor Type Trap Density in Semi-insulating GaN Layers <i>T. Tanaka, N. Ito, M. Akutsu, K. Chikamatsu, S. Takado and K. Nakahara, ROHM Co., Ltd. (Japan)</i>		11:25 O-7-3 Investigation of Carbon Nanotube Memory Cell Array Program Characteristics <i>S.Y. Ning¹, T.O. Iwasaki¹, E. Yanagizawa¹, S. Hachiya¹, G. Rosendale², M. Manning², D. Viviani², T. Rueckes² and K. Takeuchi¹, ¹Chuo Univ. and ²Nantero Inc. (Japan)</i>	
11:30 H-7-4 Controlled Photon Emission of Colloidal PbS Quantum Dot by Using Photonic Dot Made of Optical Polymer and Silicon <i>T. Nozaka and K. Mukai, Yokohama National Univ. (Japan)</i>		11:45 K-7-4 Impact of Hole Shape on Program Vt Distribution in Gate-All-Around 3D Flash Memory <i>C.H. Cheng, C.W. Lee, K.W. Wu, S.H. Ku, N.K. Zous, L. Liu, S.W. Huang, Y.W. Chang, I.J. Huang, A. Suzuki, T.C. Lu, W.P. Lu and K.C. Chen, Macronix Int'l. Co. Ltd. (Taiwan)</i>	11:45 M-7-4 GaAs/In_{0.2}Ga_{0.8}As Fin-Array-Esaki Tunnel Diodes Fabricated on (001) Silicon by Aspect Ratio Trapping <i>Q. Li, Y. Han and K.M. Lau, HKUST (China)</i>		11:45 O-7-4 A 1.0 V Operation, 65% Faster Set/Reset Voltage (3V) Generator for 3D-integrated ReRAM and NAND Flash Hybrid Solid-State Drive <i>M. Tanaka, S. Hachiya, T. Ishii, S.Y. Ning and K. Takeuchi, Chuo Univ. (Japan)</i>	
11:45 H-7-5 (Late News) Characterization and Topological Properties of Bi₂Se₃ Thin Film Grown by using Physical Vapor Deposition <i>Y.C. Lin, Y.S. Chen, C.C. Lee, J.K. Wu, H.Y. Lee and Y.H. Chang, National Taiwan Univ. (Taiwan)</i>			12:00 M-7-5 The Effects of AlN Passivation Layer to Metal Work-Function and Band Alignment of Metal Oxide Semiconductor Devices <i>H.B. Do, Q.H. Luc, M.T.H. Ha, S.H. Huynh, Y.C. Lin and E.Y. Chang, NCTU (Taiwan)</i>			

Wednesday, September 30

1F Middle-Sized Hall A	1F Middle-Sized Hall B	1F 101	1F 102	1F 107a	1F 107b	1F 108a
A-7: III-V Devices and Related Technologies		C-7: Crystalline Silicon Photovoltaics	D-7: Nanowire Synthesis and Properties II		F-7: Biosensors	G-7: Organic Devices II
12:00 A-7-6 Fabrication of Two-Color Surface Emitting Device of a Coupled Cavity Structure with InAs QDs Formed by Wafer-Bonding <i>H. Ota, C. Harayama, T. Maekawa, X.M. Lu, N. Kumagai, T. Kitada and T. Isu, Tokushima Univ. (Japan)</i> 12:15 A-7-7 Demonstration of Two-Wavelength Lasing in a GaAsP Ring/Fabry-Perot Composite Cavity Semiconductor Laser <i>A.K. Saha and T. Suhara, Osaka Univ. (Japan)</i>		12:00 C-7-6 Activation of Silicon Implanted with Phosphorus and Boron Atoms by Microwave Rapid Annealing <i>S. Kimura, M. Hasumi, K. Ota and T. Sameshima, Tokyo Univ. of Agri. & Tech. (Japan)</i> 12:15 C-7-7 Combination Accelerating Test for Crystalline Si Photovoltaic Modules <i>A. Masuda¹, C. Yamamoto¹, N. Uchiyama¹, K. Ueno² and T. Yamazaki^{2,1} AIST and ²Choshu Industry Co., Ltd. (Japan)</i>	12:15 D-7-6 X-ray Diffraction Study of Evolution of Polytypes in Au-assisted GaAs Nanowires <i>M. Takahashi^{1,2}, M. Kozu^{1,2} and T. Sasaki¹, ¹JAEA and ²Univ. of Hyogo (Japan)</i>		12:15 F-7-6 Monitoring of Hydroxyapatite Crystal Formation using Field Effect Transistor <i>T. Kajisa¹ and T. Sakata², ¹PROVIGATE Inc. and ²Univ. of Tokyo (Japan)</i>	12:15 G-7-6 (Invited) Organic-Assisted Oriented Attachment of Silver Nanosheets <i>S. Ekgasit and P. Jangtawee, Chulalongkorn Univ. (Thailand)</i>

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2F 201	2F 202	2F Small Hall	2F 204	2F 206	2F 207	1F 108b
H-7: Quantum Devices			M-7: III-V Materials & Devices			
12:00 H-7-6 (Invited) Ultraclean Carbon Nanotube Quantum Dots Coupled to Superconducting Impedance Matching Circuits <i>M. Jung¹, T. Hasler¹, V. Ranjan¹, G. Puebla Hellmann^{1,2}, A. Wallraff² and C. Schonenberger¹,</i> ¹ Univ. of Basel and ² ETH Zurich (Switzerland)			12:15 M-7-6 Withdrawn			